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Day: Monday Date: 3/12/2007

Time: 16:25:35

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1	US 7170176 B2 US	20070130	Semiconductor device Compressor	257/758 92/155	257/59; 257/72; 257/E21.589; 257/E29.112; 438/296; 438/665	Ishikawa; Akira et al.
	7156014 B2		-	92/103		Takahiro et al.
1	US 7134382 B2	20061114	Paint composition and sliding part	92/155	92/71	Murase; Hitotoshi et al.
	US 7098087 B2	20060829	Manufacturing method of semiconductor device	438/151	257/E21.279; 257/E21.293; 257/E21.413; 257/E27.111; 257/E29.278; 257/E29.293; 438/149; 438/164; 438/788; 438/792	Akimoto; Kengo et al.
1	US 7087885 B1	20060808	Particle size distribution measuring apparatus and method	250/222.2	356/336	Yamaguchi; Tetsuji
1	US 7042557 B2	20060509	Sample supplying device for a dry particle-size distribution measuring apparatus and method	356/36	221/180; 356/336	Yamaguchi; Tetsuji et al.
1	US 7021194 B2	20060404	Sliding component and compressor	92/71		Shimo; Toshihisa et al.
1	US 7009021 B2	20060307	Paint composition, proces for producing wear-resistant coating film using the same, and wear-resistant coating	528/10	428/412; 428/446; 528/15; 528/17; 528/18	Tani; Masaaki et al.

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			film comprising			
			the same			
1 .	US 6988875 B2	20060124	Lubricating structure in fixed displacement	417/269	184/6.17; 92/12.2	Shintoku; Noriyuki et al.
			piston type compressor			
	US 6971639 B2	20051206	Orifice devices with lock mechanisms, vibration absorption devices having the orifice devices, and methods of assembling the orifice devices	267/140.13		Okada; Hiroki et al.
1	US 6864979 B2	20050308	Particle size distribution measuring apparatus	356/336	356/338	Yamaguchi; Tetsuji
1	US 6862975 B2	20050308	Apparatus for lubricating piston type compressor	92/154	92/156; 92/71	Shintoku; Noriyuki et al.
1	US 6855768 B2	20050215	Coating composition, coating method, and coated article	525/100	106/287.11; 525/102	Matsumura; Kazuyuki et al.
1	US 6838509 B2	20050104	Phenolic resin composite material	524/447	524/425; 524/445; 524/449; 524/494	Shimo; Toshihisa et al.
1	US 6837691 B2	20050104	Refrigeration suction mechanism for a piston type compressor and a piston type compressor	417/269		Tarutani; Tomoji et al.
1	US 6773001	20040810	Vibration isolation mount	267/140.4	267/294	Saiki; Akio et al.

	B2					
1	US 6766811 B2	20040727	Method of removing smear from via holes	134/1.3	216/13; 216/17; 216/18; 216/57; 216/65; 438/704; 438/708; 438/725	Shimo; Toshihisa et al.
1	US 6755401 B2	20040629	Fluid-filled vibration damping device	267/140.11	267/140.13	Akasa; Shouji et al.
1	US 6744507 B2	20040601	Dry particle distribution measuring apparatus and method	356/336		Yamaguchi; Tetsuji
1	US 6694864 B2	20040224	Swash plate type compressor	92/71	228/115	Kato; Takayuki et al.
1	US 6677047 B2	20040113	Coating composition, coating method, and coated article	428/447	106/287.11; 526/279; 528/38	Matsumura; Kazuyuki et al.
1	US D483756 S	20031216	Operation controller for electronic computers	D14/356		Tanaka; Keita et al.
1	US . D479235 S	20030902	Portable information terminal	D14/346		Tanaka; Keita et al.
1	US D479234 S	20030902	Portable information terminal	D14/346		Tanaka; Keita et al.
1	US 6589021 B2	20030708	Single-headed piston type swash plate compressor	417/222.2	92/71	Kato; Takayuki et al.
1	US 6568918 B2	20030527	Lubrication coating for the sliding portion of a swashplate compressor	417/269	184/6.17; 417/222.2; 92/155; 92/71	Sugioka; Takahiro et al.
1	US D474184	20030506	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki

	S					et al.
1	US D473875 S	20030429	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki et al.
1	US D473874 S	20030429	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki et al.
1	US 6538051 B1	20030325	Aqueous coating agent of hydrophilic resin, MoS2 and Sb2S3 and/or Sb2S5	523/402	524/560; 524/588; 524/601	Ikezawa; Atsushi et al.
1	US 6503046 B1	20030107	Apparatus and method for extracting a single bar from a plurality of bars	414/730	414/745.1; 414/745.5; 414/745.7	Saiki; Akio et al.
1	US 6473177 B2	20021029	Particle-size distribution measuring apparatus	356/336	356/335	Yamaguchi; Tetsuji
1	US 6465388 B1	20021015	Process for forming a film with photocatalytic function	502/159	106/287.1; 106/287.19; 427/412.1; 502/158; 502/527.12; 502/527.13	Hozumi; Atsushi et al.
1	US 6454545 B1	20020924	Compressor	417/269	137/856; 137/857; 417/571	Ikeda; Hayato et al.
1	US 6402483 B1	20020611	Double-headed piston compressor	417/269	417/312; 417/540	Kawamura; Hisato et al.
1	US D455037 S	20020402	Case for magnetic disks	D6/632	D3/201; D6/407	Baba; Noriaki
1	US 6364629 B1	20020402	Valve structure with configured retainer	417/269		Shintoku; Noriyuki et al.
1	US 6357340 B1	20020319	Piston compressor piston	92/155	92/248	Kato; Takayuki et al.
1	US 6334977	20020101	Powder material for powder	420/70	420/34; 75/228;	Matsui; Masakazu

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	B1		plasma overlaying and powder plasma overlaying metal		75/246; 75/255	et al.
1	US 6296457 B1	20011002	Discharge pulsation damping apparatus for compressor	417/312	181/403; 417/269	Shintoku; Noriyuki et al.
1	US 6293768 B1	20010925	Piston type compressor	417/312	417/269; 92/71	Shintoku; Noriyuki et al.
1	US 6276673 B1	20010821	Fluid-filled active vibration damping device having stabilizing member for stabilizing oscillating member	267/140.14	÷ .	Hibi; Masayuki et al.
1	US 6250648 B1	20010626	Gasket for sealing a refrigerant compressor	277/652	277/594	Ikeda; Hayato et al.
1	US 6231315 B1	20010515	Compressor having a value plate and a gasket	417/269	137/856; 417/560	Ikeda; Hayato et al.
1	US 6206351 B1	20010327	Pneumatically operated active vibration damping device having pressure regulating device	267/140.14	267/140.13	Hamada; Masaaki et al.
1	US 6192784 B1	20010227	Swash plate compressor	92/71	92/155	Kato; Takayuki et al.
1	US 6191853 B1	20010220	Apparatus for measuring particle size distribution and method for analyzing particle size	356/336	250/575; 356/337; 356/338	Yamaguchi; Tetsuji et al.

			distribution			
1	US	20010213	Gasket for	277/594	277/639;	Ikeda;
•	6186514		sealing a		277/644	Hayato et
	B1		refrigerant			al.
	101	,	compressor			***
1	US	20000530	Gasket for	277/652	277/594	Ikeda;
1	6068265	20,000330	sealing a	2171032	2111394	Hayato et
	A		refrigerant	*		al.
	A		_			ai.
1	110	10001116	compressor	D14/434		Cucana
1	US	19991116	Connecting	D14/434		Sugano; Yoshihiko
	D416548		device for			
	S		peripheral			et al.
			equipment of an			
			electronic			
	110	10001001	computer	417/260	00/51	70
1	US	19981201	Reciprocating	417/269	92/71	Tarutani;
	5842836		piston type			Tomoji et
	A		refrigerant			al.
			compressor			
	_		having a			
			housing with			
		1	enhanced			
			sealing function			
1	US	19981124	Valve	137/856	137/855	Shintoku;
	5839472		mechanism of a			Noriyuki et
	Α		compressor			al.
1	US	19980922	Piston-type	92/71	417/269	Ikeda;
	5809865		compressor with			Hayato et
	Α		reduced			al.
			vibration			
1	US	19980818	Swash plate type	417/269	184/6.17;	Ikeda;
	5795139		refrigerant		62/470	Hayato et
	A		compressor with			al.
		1	improved			
	'		internal			
			lubricating			
			system		-	
1	US	19970218	Piston type	417/269	137/856;	Tarutani;
	5603611		compressor with		417/569;	Tomoji et
	Α		simple but		417/571	al.
			vibration-			
			reducing suction			
			reed valve			
			mechanism			
1	US	19950110	Discharge valve	137/856		Kawai;
1 ~	5379799		apparatus for			Katsunori
	1 3 1 / 9 / 9 9	1	i apparains for			Natsunon

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	A		compressor			et al.
1	US	19940201	Exhaust gas	60/39.5	60/39.182	Yamaguchi;
	5282355		NO.sub.x			Tetsuji
	A		removal system			
1	US	19940111	Infrared	250/347	250/339.07;	Yamaguchi;
	5278413		microscopic		250/339.11	Tetsuji et
	Α		spectrometer			al.
1	US	19920728	Stress relief	257/712	257/677;	Yamaguchi;
	5134463		layer providing		257/E21.512;	Tetsuji
	Α		high thermal		257/E23.028;	
			conduction for a		257/E23.109;	
	·		semiconductor		257/E23.112;	
			device		257/E23.14;	
					257/E25.016;	
					361/707;	
					361/714	
1	US	19910122	Superconducting	332/173	331/187	Mouri;
	4987390		reversible			Kaneo et al.
	Α		variable			
			inductor			
1	US	19831129	Automatic bar	82/126	414/18;	Uehara;
	4417491		material feeding		414/746.4;	Sukehiro et
	A		apparatus		414/746.7;	al.
				l	82/153	